PATENT
Docket No. 150.01150103

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Sandhu	Group Art Unit:	Unassigned
Serial No.:	10/771,043	Examiner:	Unassigned
Confirmation No.:	Unassigned		
Filed:	February 3, 2004		
For:	DETECTION DEVICES, METHODS AND SYSTEMS FOR GAS PHASE MATERIALS		

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with C.F.R. §§ 1.97 *et. seq.*, the materials enclosed herewith are brought to the attention of the Examiner as possibly being of interest in connection with the above-identified patent application. Per M.P.E.P. § 609, the information cited in the present Information Disclosure Statement shall not be construed to be an admission that the information is, or is considered to be, material to patentability. Consideration of each of the documents listed on the attached 1449 forms is respectfully requested. As this patent application was filed after June 30, 2003, copies of the U.S. patents and U.S. patent application publications listed on the attached 1449 forms have not been submitted. Pursuant to the provisions of M.P.E.P. §609, Applicant further requests that a copy of the 1449 forms, marked as being considered and initialed by the Examiner, be returned with the next Official Communication.

This application is a continuation of U.S. Patent Application Serial No. 10/266,797, filed October 8, 2002, which is a continuation of U.S. Patent Application Serial No. 09/652,634, filed August 31, 2000 and issued as U.S. Patent No. 6,479,297 on November 12, 2002. In accordance with 37 C.F.R. §1.98(d), copies of documents previously cited by or

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submitted to the U.S. Patent and Trademark Office in connection with Applicant's prior application(s) listed above, are not included herewith.

It is believed that no fee is due, as this Information Disclosure Statement is filed prior to the receipt of any Action on the merits. However, in the event a fee is due, please charge any fee or credit any overpayment to Account No. 13-4895.

The Examiner is invited to contact Applicant's Representatives at the below-listed telephone number, if they can be of any assistance during prosecution of the present application.

CERTIFICATE UNDER 37 C.F.R. 1.8:

The undersigned hereby certifies that this paper is being transmitted by facsimile in accordance with 37 CFR §1.6(d) to the Patent and Trademark Office, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 29th day of April, 2004, at 3:20pm (Central Time).

Name: SUE E. OLSON

29 APRIL 2004
Date

Respectfully submitted for
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	Information Disclosure Statement mailed:	April 29, 2004

U.S. PATENT DOCUMENTS

Examiner Initial	Copy Enclosed	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
		3,585,073	06/15/71	Veenstra et al.			
		3,890,703	06/75	Frazee et al.			
		4,433,320	02/21/84	Murata et al.			
		4,442,422	04/10/84	Murata et al.			
		4,677,416	06/30/87	Nishimoto et al.			
		4,911,892	03/27/90	Grace et al.			
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		5,331,287	07/19/94	Yamagishi et al.			
		5,337,018	08/09/94	Yamagishi			
		5,756,879	05/26/98	Yamagishi et al.			
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		5,906,726	05/25/99	Schneider et al.			
		6,280,604	08/28/01	Allen et al.			
		6,436,246	08/20/02	Sandhu			
		6,479,297	11/12/02	Sandhu			
		6,689,321	02/10/04	Sandhu			
		US 2003/0138958	07/24/03	Blalock			

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Examiner Initial	Copy Enclosed	Document Number	Date	Country	Class	Subclass	Translation Yes	Translation No
		1,151,482	05/07/69	Great Britain				
		1,576,658	08/01/69	France (w/abstract)				X

EXAMINER	Date Considered

*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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		2-293644	12/04/90	Japan (w/abstract)				X
		386,660	09/12/90	EP (w/abstract)				X
		3-48748	03/01/91	Japan (w/abstract)				X
		60-210752	10/85	Japan (w/abstract)				X
		2-69658	03/90	Japan				X

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

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		Aizenshtein et al., "Method of measurement of the rate of deposition of pure metals from the gas phase," *Chem. Abstr.*, 1966; *64*: abstract 1747e.
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OMB No. 0651-0011

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		Koda et al., "Radioactivation determination of ruthenium," *Kyoto Daigaku Genshiro Jikkensho Gakujutsu Koenkai Koen Yoshishu*, 1976;*10*: 25-27.
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		Takayama et al., "Gas-Sensitive Ag Ion Conduction in Semiconducting ZnO Thin Films," *Solid State Ionics*, 1989; *35*: 411-415.
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